## INTERNATIONAL-TYPE SEARCH REPORT

Search request No.
PCT/SE2004/001742

Box No. II Observations where certain claims were found unsearchable (Continuation of item 2 of first sheet)						
This international-type search report has not been established in respect of certain claims for the following reasons:						
Claims Nos.:     because they relate to subject matter not required to be searched by this Authority, namely:						
Claims Nos.:     because they relate to parts of the national application that do not comply with the prescribed requirements to such an extent that no meaningful international-type search can be carried out, specifically:						
Box No. III Observations where unity of invention is lacking (Continuation of item 3 of first sheet)						
This International Searching Authority found multiple inventions in this national application, as follows:						
See next page						
As all required additional search fees were timely paid by the applicant, this international-type search report covers all searchable claims.						
As all searchable claims could be searched without effort justifying an additional fee, this Authority did not invite payment of any additional fee.						
3. As only some of the required additional search fees were timely paid by the applicant, this international-type search report covers only those claims for which fees were paid, specifically claims Nos.:						
4. No required additional search fees were timely paid by the applicant. Consequently, this international-type search report is restricted to the invention first mentioned in the claims; it is covered by claims Nos.:						
Remark on Protest The additional search fees were accompanied by the applicant's protest.						
No protest accompanied the payment of additional search fees.						

Form PCT/ISA/201 (continuation of first sheet (2)) (January 2004)

### INTERNATIONAL-TYPE SEARCH REPORT

Search request No. PCT/SE2004/001742

The International Search Authority considers that there are 3 inventions covered by the claims indicated as follows:

- I: Claims 1-13 and 14-22 directed to a method and an apparatus for magnetron sputtering comprising a stationary magnetic mirror trap in order to guide the plasma flow towards and past or beyond the position of the work piece and therefrom back again.
- II: Claims 23 and 24 directed to an apparatus for magnetron sputtering comprising filtering plates for adsorption of reactive gas ions and neutral particles.
- III: Claim 25 directed to an apparatus for magnetron sputtering in which sputtering-, reactive and/or processing gases are supplied directly to the work piece processing part of the chamber.

As the invention according to claim 25 could be searched without any additional effort, the search report covers inventions I and III above.

## INTERNATIONAL SEARCH REPORT

International application No.

PCT/SE 2004/001742

	PC1/SE 2004	7001742			
A. CLASSIFICATION OF SUBJECT MATTER					
IPC7: H01J 37/34, C23C 14/35 According to International Patent Classification (IPC) or to bot	h national classification and IPC				
B. FIELDS SEARCHED					
Minimum documentation searched (classification system followe	ed by classification symbols)				
IPC7: C23C, H01J					
Documentation searched other than minimum documentation to	the extent that such documents are included	in the fields searched			
SE,DK,FI,NO classes as above					
Electronic data base consulted during the international search (n	ame of data base and, where practicable, search	ch terms used)			
EPO-INTERNAL, WPI DATA, PAJ, INSPEC					
C. DOCUMENTS CONSIDERED TO BE RELEVAN	т				
Category* Citation of document, with indication, where	appropriate, of the relevant passages	Relevant to claim No.			
20 June 2000 (20.06.2000) line 10 - column 7, line	US 6077403 A (MASAHIKO KOBAYASHI ET AL), 20 June 2000 (20.06.2000), column 3, line 10 - column 7, line 19; column 7, line 65 - column 8, line 50, figures 1,4, abstract				
to control ion/neutral flo substrate during magnetro	I. Petrov et al Use of an externally applied axial magnetic field to control ion/neutral flux ratios incident at the substrate during magnetron sputter deposition J. Vac. Sci. Technol. A 10(5), Sept/Oct 1992				
AN 4298806 see page 3288-3287	),Sept/OCt 1332				
X Further documents are listed in the continuation of	Box C. X See patent family anne	х.			
* Special categories of cited documents:  "A" document defining the general state of the art which is not considered to be of particular relevance  "T" later document published after the international filing date or priority date and not in conflict with the application but cited to understand the principle or theory underlying the invention					
to be of particular relevance  'E" earlier application or patent but published on or after the internation filing date  'L" document which may throw doubts on priority claim(s) or which is	onal "X" document of particular relevance; the	claimed invention cannot be cred to involve an inventive			
cited to establish the publication date of another citation or other special reason (as specified)  O' document referring to an oral disclosure, use, exhibition or other means  P'' document published prior to the international filing date but later to	considered to involve an inventive ste combined with one or more other suc being obvious to a person skilled in the	-			
the priority date claimed	document member of the same patent	family			
Date of the actual completion of the international search	Date of mailing of the international	search report			
12 April 2005	1 4 -04- 2605	1 4 -04- 2605			
Name and mailing address of the ISA/	Authorized officer				
Swedish Patent Office  Box 5055, S-102 42 STOCKHOLM  Facsimile No. + 46 8 666 02 86  Bo Gustavsson/MN  Telephone No. + 46 8 782 25 00					
Telephone 110. 1 40 8 702 23 00					

## INTERNATIONAL SEARCH REPORT

International application No.
PCT/SE 2004/001742

		101/3L 2004	
C (Continu	ation). DOCUMENTS CONSIDERED TO BE RELEVANT		
Category*	Citation of document, with indication, where appropriate, of the relev	Relevant to claim No	
A	US 5196105 A (ALBERT FEUERSTEIN ET AL), 23 March 1993 (23.03.1993), see whole docu	1-22	
A	P. Losbichler et al Surface andCoatings Technology 97 (1997) 567-573 Non-rectively sputtered TiN and TiB2 films: influence of activation energy on film growth		1-22,25
x	EP 0347567 A2 (LEYBOLD AKTIENGESELLSCHAFT), 27 December 1989 (27.12.1989)		25
			·
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Form PCT/ISA/210 (continuation of second sheet) (January 2004)

# INTERNATIONAL SEARCH REPORT

Information on patent family members

01/04/2005

International application No.

PCT/SE 2004/001742

US	6077403	A	20/06/2000	JP TW	11001770 A 452601 B	06/01/1999 00/00/0000
US	5196105	A	23/03/1993	DE DE EP JP JP	4038497 C 59101796 D 0489239 A,B 2556637 B 4289167 A	20/02/1992 00/00/0000 10/06/1992 20/11/1996 14/10/1992
EP.	0347567	A2	27/12/1989	DE JP US	3821207 A 2054764 A 4931169 A	28/12/1989 23/02/1990 05/06/1990